<u>IN THE CLAIMS</u>:

Please cancel Claims 32 to 61 and 65 to 68 without prejudice or disclaimer of subject matter. Please amend Claims 63, 69 and 71, and add Claims 73 to 75 as follows. The claims as pending in the subject application read as follows:

1. to 61. (Cancelled)

62.   (Previously Presented) A manufacturing system, comprising:

a computer which provides a database;

a first manufacturing factory having a first exposure apparatus and a first LAN system capable of accessing the database; and

a second manufacturing factory, located at a remote location from said first manufacturing factory, having a second exposure apparatus and a second LAN system capable of accessing the database,

wherein the database stores maintenance information concerning the first and second exposure apparatuses, the maintenance information including status information, of the first and second exposure apparatuses, which was received from said first and second LAN systems and response information which was used for handling a problem indicated by the received status information.

63.   (Currently amended) A device manufacturing method, comprising:

exposing a wafer by the <u>first</u> exposure apparatus of the manufacturing system defined in Claim 62; and

developing the exposed wafer.

64.   (Previously Presented) A product being manufactured by the manufacturing system defined in Claim 62.

65. to 68.   (Cancelled)

69.   (Currently amended) A manufacturing system, comprising:

a computer which provides a database storing maintenance information;

a first manufacturing factory having a first exposure apparatus and a first LAN system capable of accessing the database; and

a second manufacturing factory, located at a remote location from said first manufacturing factory, having a second exposure apparatus and a second LAN system capable of accessing the database,

wherein the ~~computer provides a database storing~~ maintenance information includes information concerning the first and second exposure apparatuses, and wherein the computer ~~concerning the industrial equipment and~~ comprises a communication security system which inhibits unauthorized entities from accessing the database.

70.   (Previously Presented) The system according to Claim 69, wherein the maintenance information includes status information, of the first and second exposure apparatuses, which was received from said host computer and response information which was used for handling a problem indicated by the received status information.

71.   (Currently amended) A device manufacturing method, comprising:

exposing a wafer by the <u>first</u> exposure apparatus of the manufacturing

system defined in Claim 69; and

developing the exposed wafer.

72.   (Previously Presented) A product being manufactured by the

manufacturing system defined in Claim 69.

73.   (New) A manufacturing system, comprising:

a computer which provides a database;

a first manufacturing factory having a first exposure apparatus and being

able to access the database; and

a second manufacturing factory, located at a remote location from said first

manufacturing factory, having a second exposure apparatus and being able to access the

database,

wherein the database stores maintenance information including status

information of the first and second exposure apparatuses.

74.   (New) A device manufacturing method, comprising:

exposing a wafer by the first exposure apparatus of the manufacturing

system defined in Claim 73; and

developing the exposed wafer.

75.   (New) A product being manufactured by the manufacturing system

defined in Claim 73.